

## Electronic Patent Application Fee Transmittal

Application Number:	10821310
Filing Date:	08-Apr-2004
Title of Invention:	Apparatus for controlling gas flow in a semiconductor substrate processing chamber
First Named Inventor/Applicant Name:	Kallol Bera
Filer:	Keith Patrick Taboada
Attorney Docket Number:	8549/ETCH/DRIE/JB1

Filed as Large Entity

### **Utility Filing Fees**

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
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Basic Filing:

Pages:

Claims:

Miscellaneous-Filing:

Petition:

### **Patent-Appeals-and-Interference:**

Filing a brief in support of an appeal	1402	1	500	500
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Post-Allowance-and-Post-Issuance:

Extension-of-Time:

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Miscellaneous:</b>				
<b>Total in USD (\$)</b>				<b>500</b>